

EUROPEAN SPALLATION SOURCE

Non-Invasive Beam Profile Measurement

Overview of evaluated methods

e55



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- Beam profile measurements, mainly in the highenergy part of the linac
- Requirements:
 - The beam profile should be measured within 10 % of nominal beam width
 - The beam profile might be measured over a beam pulse or even over several pulses combined



Methods in Evaluation

- 1. Residual Gas Luminescence
- 2. Residual Gas Ionization
 - i. Detection of lons
 - ii. Detection of Electrons
- 3. Crossed Particle Beam Interaction
 - i. Electron Beam
 - ii. Ion Beam



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1. Residual Gas Luminescence



- Ion beam interacts with residual gas in a way that the gas emitts light
- This light is detected and a profile calculated

Picture: Balalykin, N. I. et al., Development of beam position and profile monitor based on light radiation of atoms excited by beam particles, Dubna, Russia: XIX Russian Particle Accelerator Conference, 2004.



1. Residual Gas Luminescence



- Problem of this method: small cross section
- Estimated photon count in ESS cryogenic section (without additional gas): <10/s



1. Residual Gas Luminescence

- Preferred method because of simple setup
- Low predicted countrate might render this method impossible in cold section
- Non-desturbing adding of gas (gas jet) has to be investigated
- At warm sections this method might be still preferred for online profile measurement
- Planned to test predictions of cold section at SNS in summer 2012



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2. Residual Gas Ionization



- Ion beam interacts with the residual gas in a way that the gas gets ionized
- Ions and/or electrons* are accelerated by an electric field towards a detector





2. i. Residual Gas Ionization

- Estimated countrate <450/(s*cm)
- Using MCPs limits operational lifetime
- Method without MCP in investigation
- Beam space charge might influence the beam imaging process
 - First simulations showed about 2.5 % beam broadening at 600 kV/m
 - Still, beam shape might be influenced



2. ii. Residual Gas Ionization

- For use of electrons a magnetic field must be overlayed
- This field must be in the region of 0.03 T
- Steering magnets within the quadrupoles might be used to correct beam
- Beam physics must be evaluated



3. Particle Beam

- A particle beam (electrons, ions) is sent perpendicular to the ion beam
- Due to coulomb interaction the particle beam is deflected
- This deflection can be used to calculate the beam profile



Picture: Peter Forck, Minimal Invasive Beam Profile Monitors for High Intense HadronBeams, IPAC 2010 Kyoto



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Conclusion

- Luminescence might be hard to achieve for cold part, maybe useful at other positions (warm section, target), or might need gas jet to increase vacuum level
- Particle beam interaction is only used at one other lab, still highly experimental
- Ionization gives a fair countrate with a proved method, because of space charge the use of electrons (adding magnets) might be necessary

